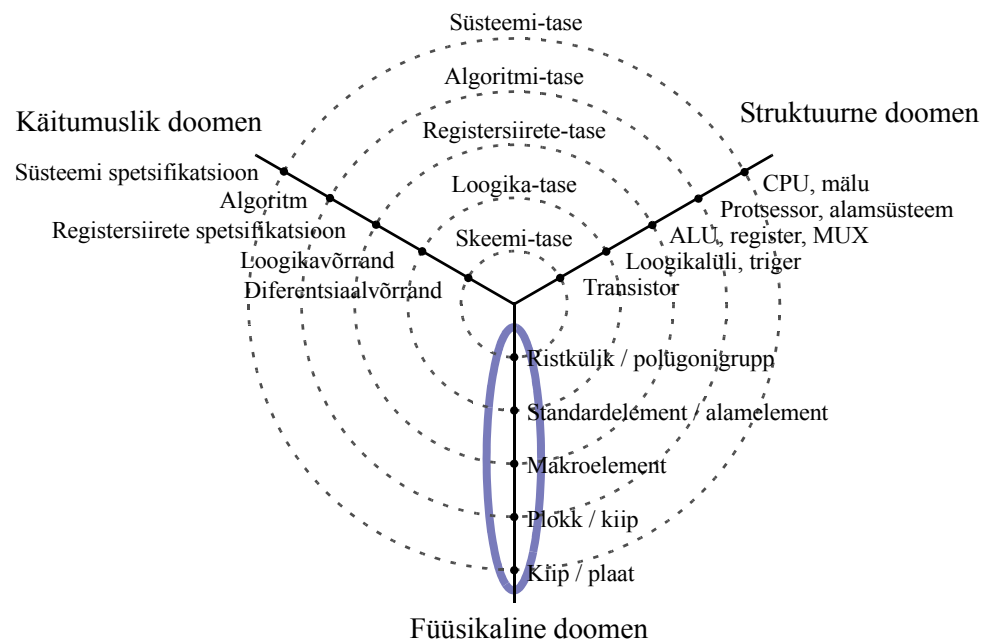
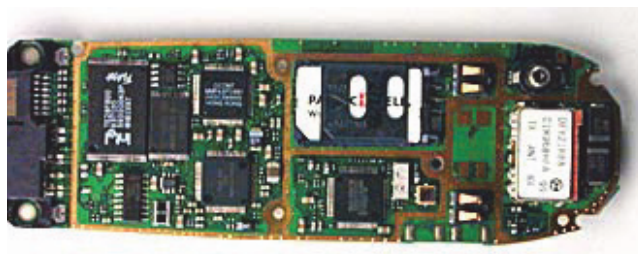
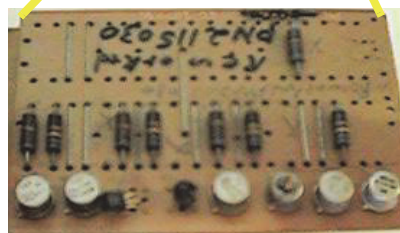
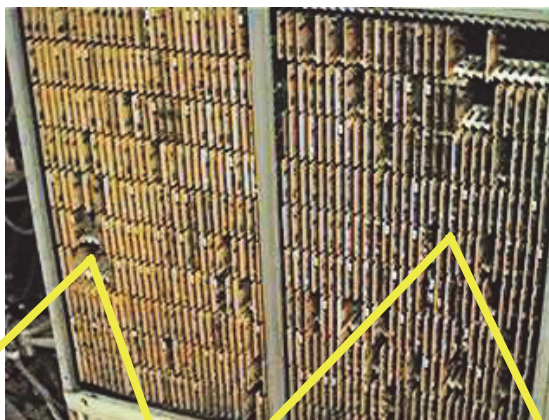
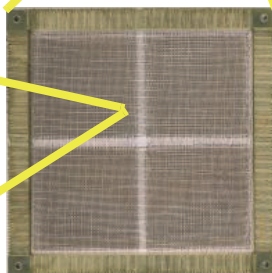
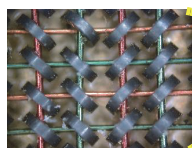
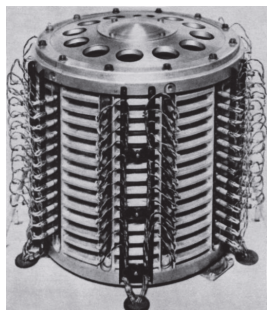
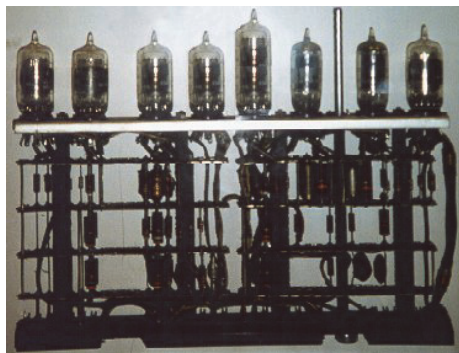


Disaini põhietapid

- **Süsteemi disain - System design**
a.k.a. Arhitektuuri süntees - Architectural-level synthesis
 - kirjeldus / spetsifikatsioon → plokk-skeem
 - makroskoopilise struktuuri määramine *ehk* kuidas on peamised ühendusplokid omavahel ühendatud
- **Loogikadisain - Logic Design**
 - plokk-skeem → loogikalülid
 - mikroskoopilise struktuuri määramine *ehk* kuidas on loogikalülid omavahel ühendatud
- **Füüsiline disain - Physical design**
a.k.a. Geomeetria süntees - Geometrical-level synthesis
 - loogikalülid → transistorid, ühendusjuhtmed, mikroskeem



Füüsiline realiseerimine – ajalugu ja tänapäev

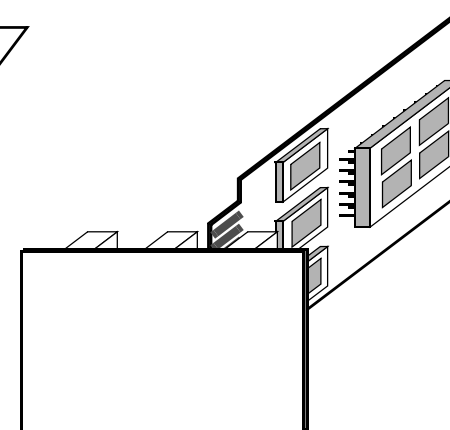
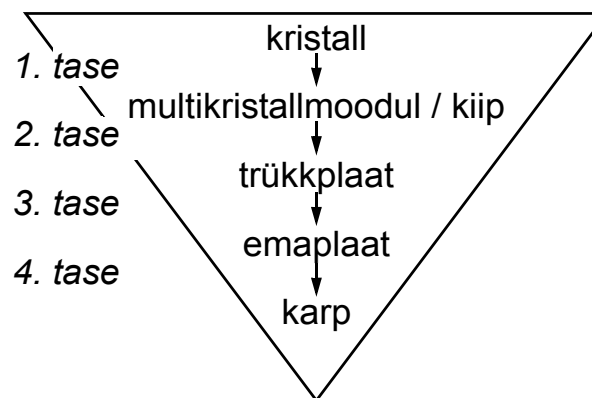


Pakendamine

- **Pakendamise hierarhia**

- **Lahendatavad ülesanded**

- elektrilised
 - mehhaanilised
 - termilised



- **Kiipide/korpuste tüübid**

- **Aukmonteeritavad (läbi trükkplaadi)**

- DIP: Dual In-line Package; PGA: Pin Grid Array
 - C-DIP, Cerdip, CPGA, TBD, HDIP, PDIP, PPGA, Shrink DIP, SIP

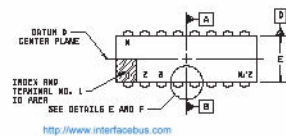
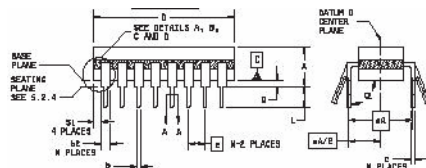
- **Pindmonteeritavad**

- PLCC: Plastic Leaded Chip Carrier; SOIC: Small Outline IC; BGA: Ball Grid Array
 - BQFP, CBGA, CFP, CPGA, CQFP, TBD, DLCC, FBGA, fpBGA, JLCC, LCC, LCCC, LFBGA, LGA, MLCC, PBGA, PQFD, PQFP, PSOP, QFP, QSOP, SOJ, SSOP, TQFP, TSOP, TSSOP, TVSOP, VQFB

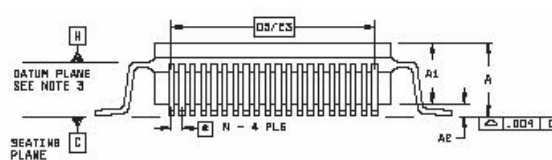
- http://www.interfacebus.com/Design_Pack_types.html

Kiipide/korpuste näited

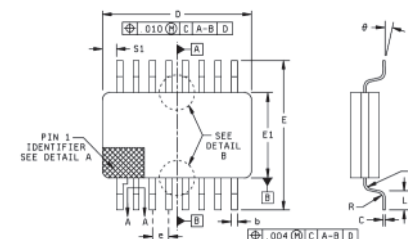
DIP



PLCC



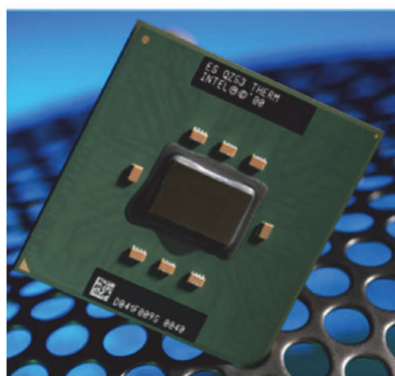
SOIC



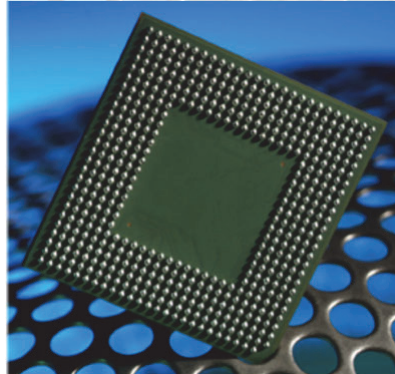
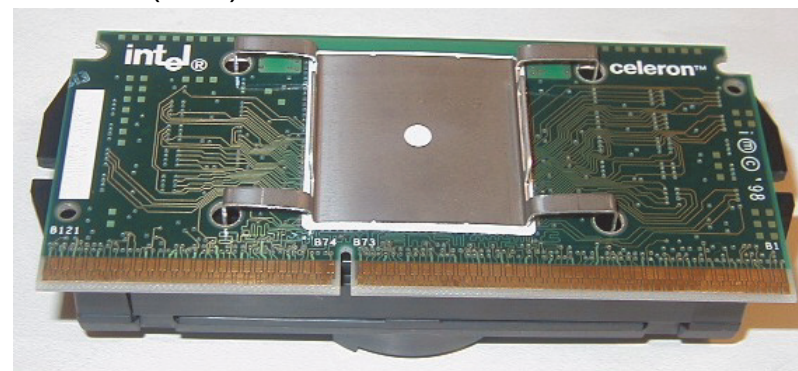
PPGA (Intel)



FCBGA (Intel)

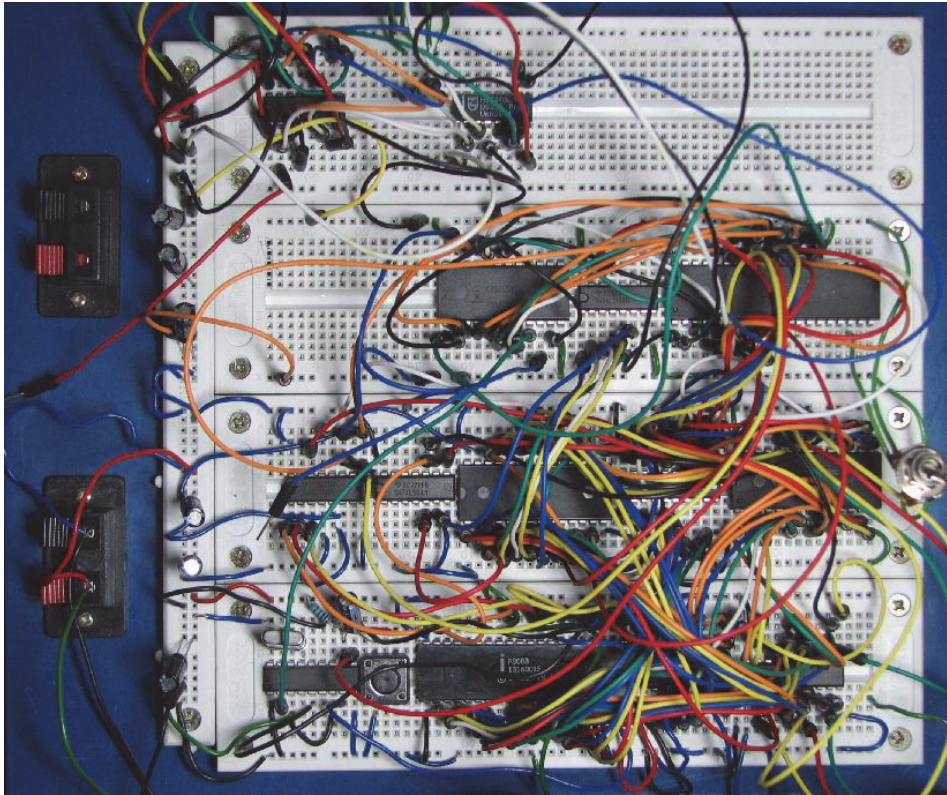


SEPP (Intel)

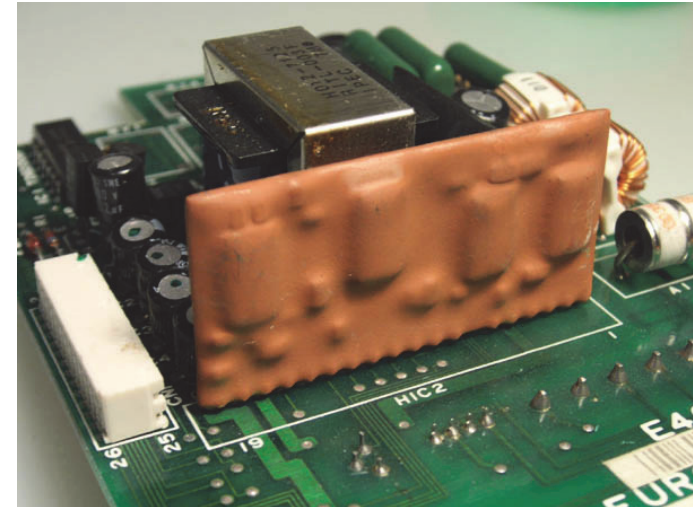


Pakendamise näited

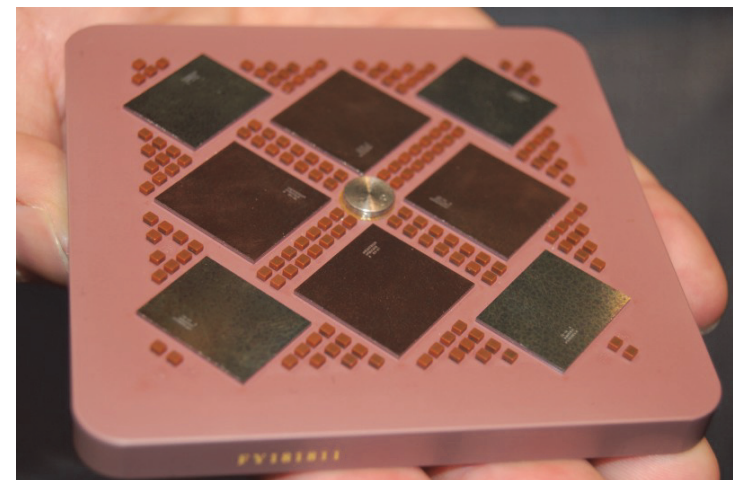
prototüüpimine



hübriidmikroskeem



ruumiline montaaž



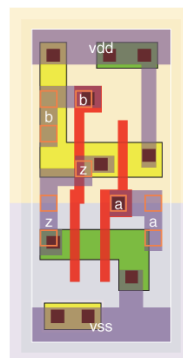
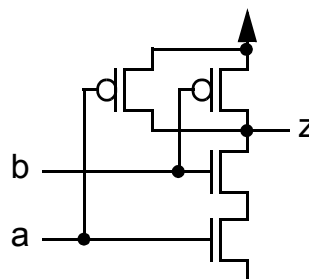
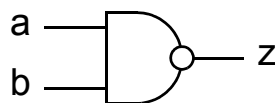
IBM POWER5

VLSI füüsiline disain

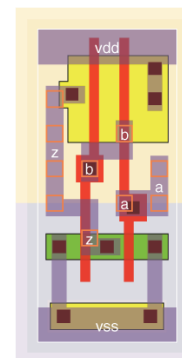
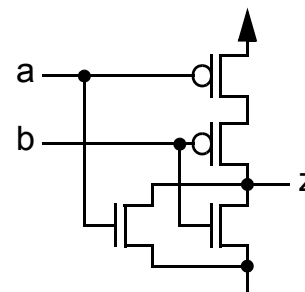
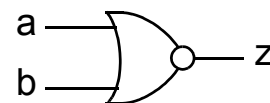
- **Loogika tase**
 - loogikaelemendid / loogikaavaldised
 - ahelad / bitid
- **Füüsika tase**
 - transistorid / traadid
- **polügonid**

vt. ka <http://www.vlsitechnology.org/>

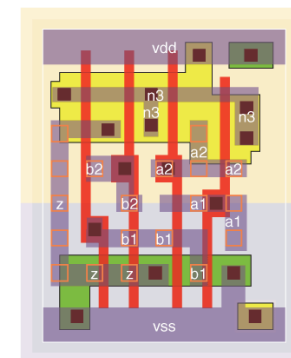
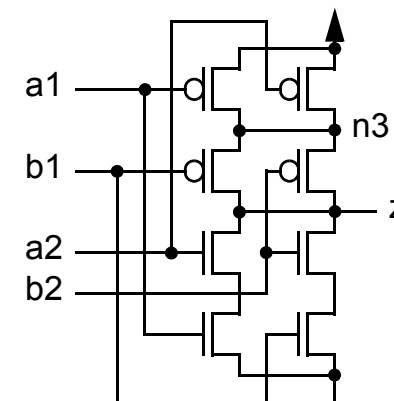
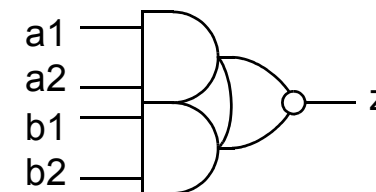
2-NAND



2-NOR

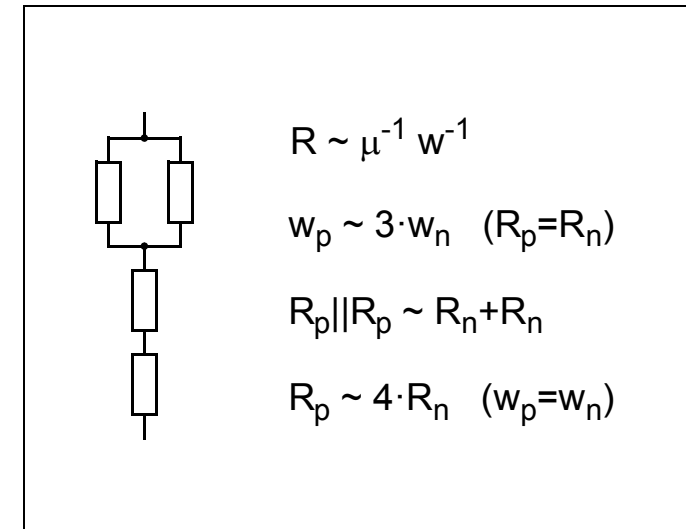
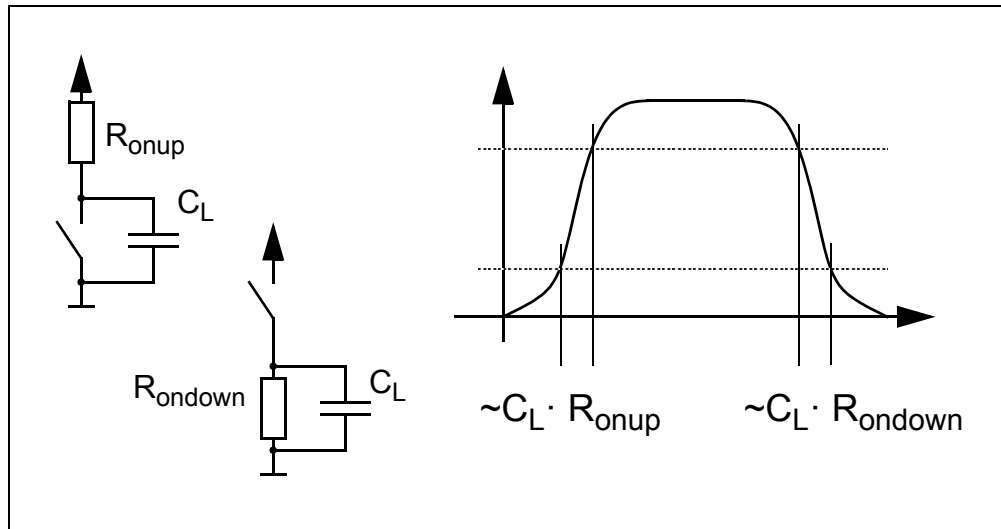
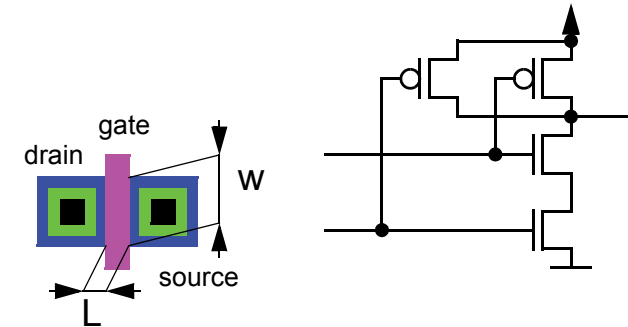


2-2-AND-NOR



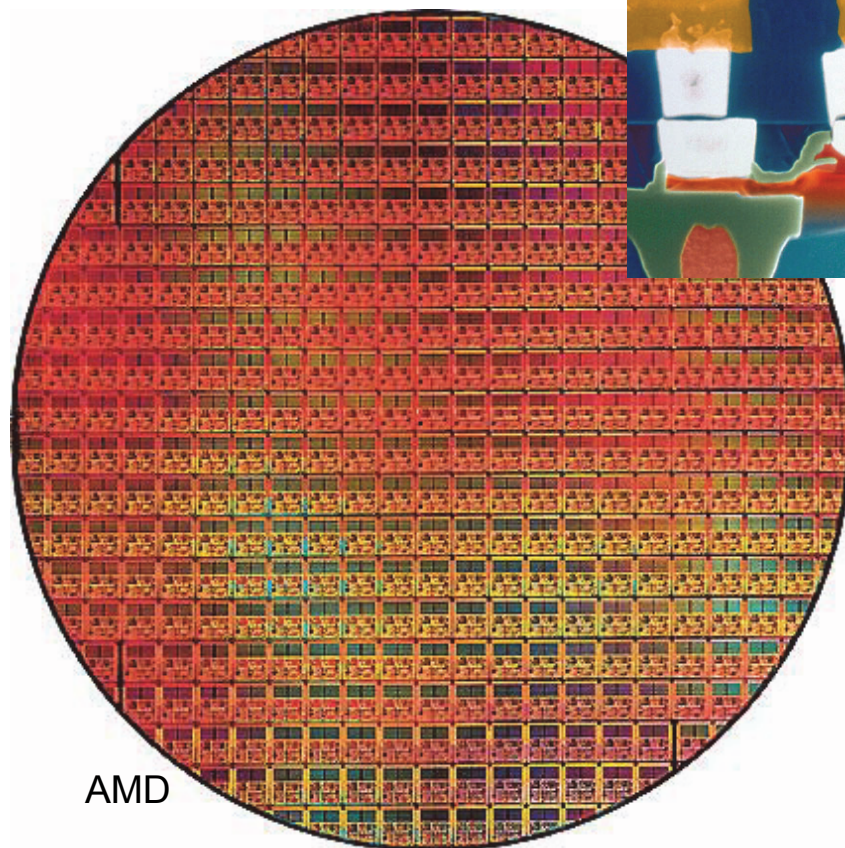
CMOS - miks NAND?

- Materjalide omadused – mobiliilsus –
 $\mu_n = 1250 \text{ cm}^2 / \text{V sec}$ & $\mu_p = 480 \text{ cm}^2 / \text{V sec}$
- $R \sim \mu^{-1}$ & $R \sim L w^{-1}$ (L - konstant)



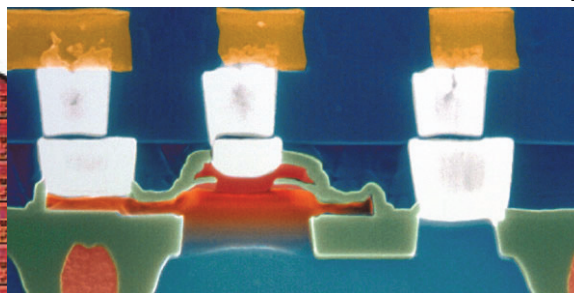
Mikroskeemide valmistamine

- maskid – ilmutamine
- söövitamine / lisamine
- pakendamine
- testimine

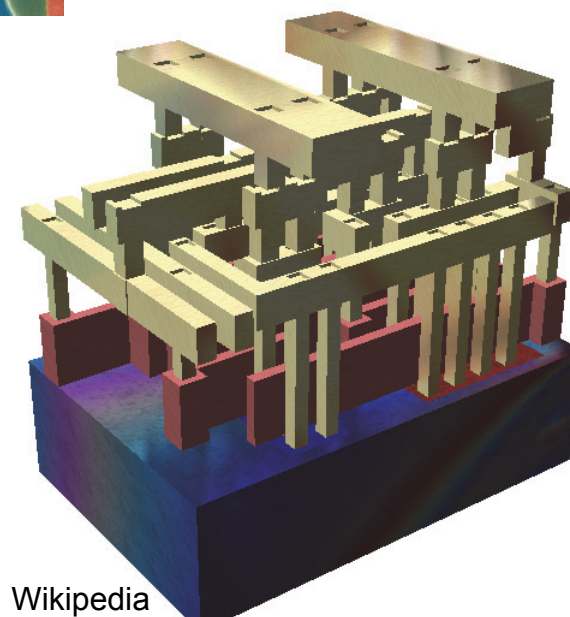
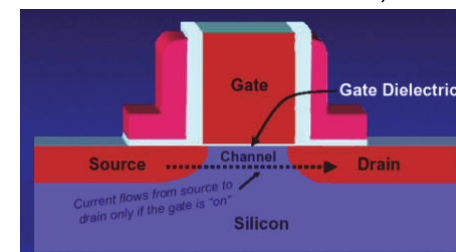


AMD

Brown University



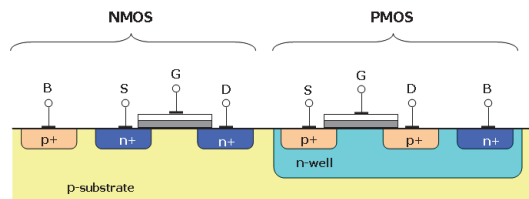
Robert Richmond, 2003



Wikipedia

Protsessi sammud

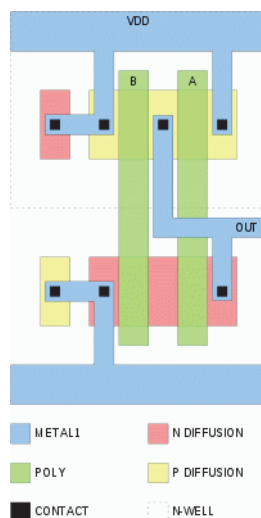
CMOS transistorid



n - elektronid [P, As, Sb]
p - augud [B, Al]

<http://jas.eng.buffalo.edu/>
CMOS inverter fabrication

2-NAND pinna laotus

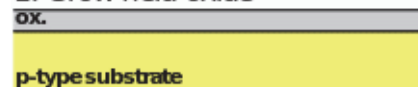


söövitamise sammud

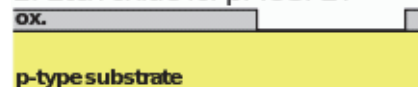
valmistamise sammud

- Prepare wafer
oxide
substrate
- Apply photoresist
PR
oxide
substrate
- Align photomask
glass
Cr
PR
oxide
substrate
- Expose to UV light
glass
Cr
PR
oxide
substrate
- Develop and remove photoresist exposed to UV light
PR
oxide
substrate
- Etch exposed oxide
PR
oxide
substrate
- Remove remaining photoresist
oxide
substrate

1. Grow field oxide



2. Etch oxide for pMOSFET



3. Diffuse n-well



4. Etch oxide for nMOSFET



5. Grow gate oxide



6. Deposit polysilicon



7. Etch polysilicon and oxide



8. Implant sources and drains



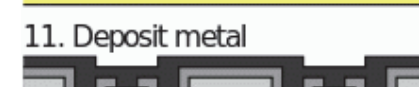
9. Grow nitride



10. Etch nitride



11. Deposit metal



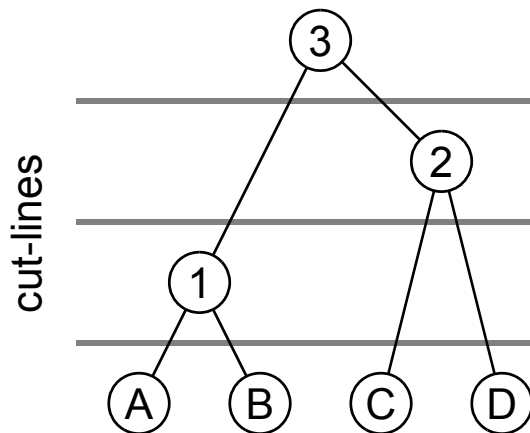
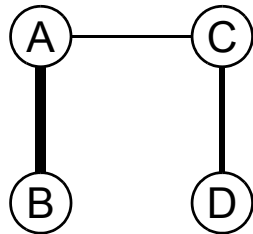
12. Etch metal



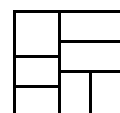
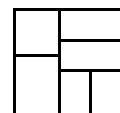
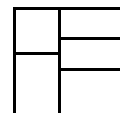
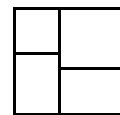
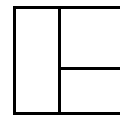
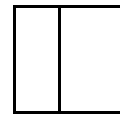
www.wikipedia.org

Pinnalaotuse süntees

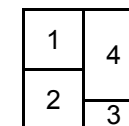
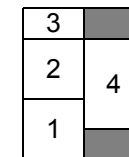
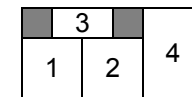
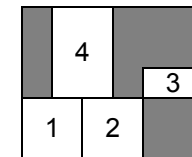
• Tükeldamine



• Pinnaplaneering



• Paigaldamine



Pinnalaotuse süntees

- **Ruutimine (trasseerimine)**

- labürindi läbimine
 - vajab palju mälu!
 - kahesuunaline otsimine
 - mitmekihiline ruutimine

Ruutimine

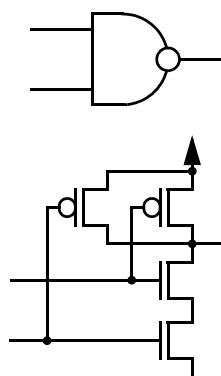
				9				9	
		9	8	9		9	8	9	
		9	8	7	8	9	8	7	8
	9	8	7	6			6	7	8
9			6	5	4	3	4	5	6
8	9		5	4	3	2	3		7
7					3	2	1	2	
6	5	4	3	2	1			5	6
7	6	5	4	3	2	1	2	3	4
8	7	6	5	4	3	2	3	4	5

4	3	2	3	4	5				
3	2	1	2	3	4	5			
2	1		1	2	3	4	5		
3	2	1	2	3	4	5			
4	3	2	3	4					
5	4		4	5	4	3	4	5	
	5		5	4	3	2	3		
				3	2	1	2		
	5	4	3	2	1			5	
		5	4	3	2	1	2	3	4
			5	4	3	2	3	4	5

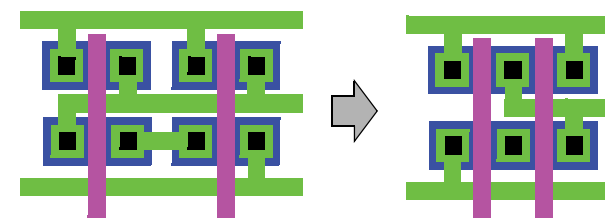
- **Pinnalaotuse optimeerimine**

- **Pinnalaotuse kontroll**

- DRC (Design Rule Check)

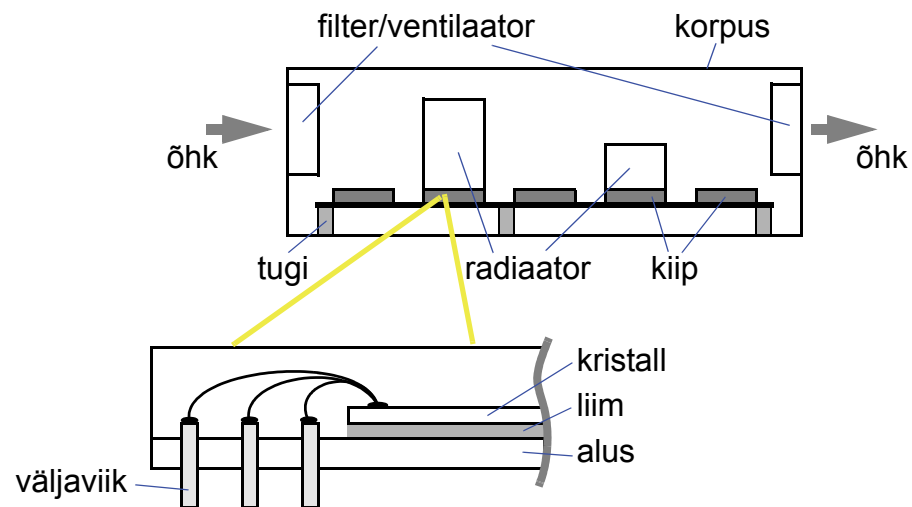
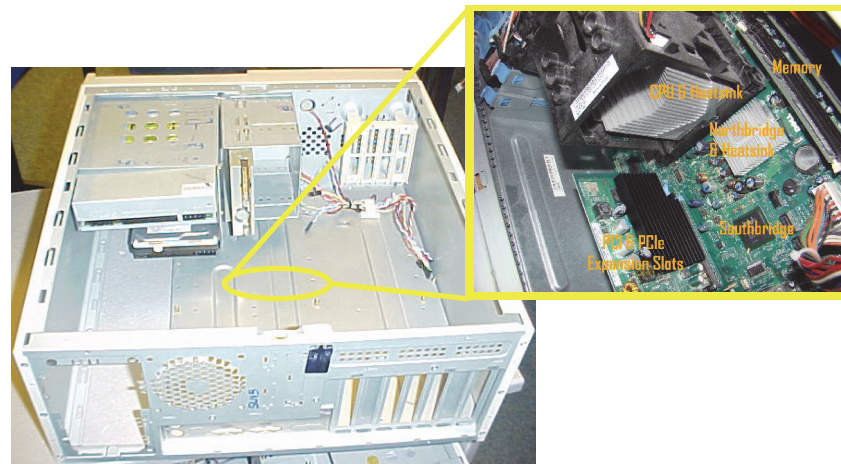


Optimeerimine



Pakendamine - korpused

- **Füüsilised nõuded ja piirangud**
 - mõõtmed, liidesed
 - vastupidavus - tolm, vibratsioon
- **Termilised nõuded ja piirangud**
 - töötemperatuuri vahemik
 - jahutamine / küte
- **Elektrilised nõuded ja piirangud**
 - elektritoide
 - kaitse - liigpinge, elektromagnetväljad
- **Ergonoomilised nõuded ja piirangud**
 - väljanägemine, kasutajaliides, müra

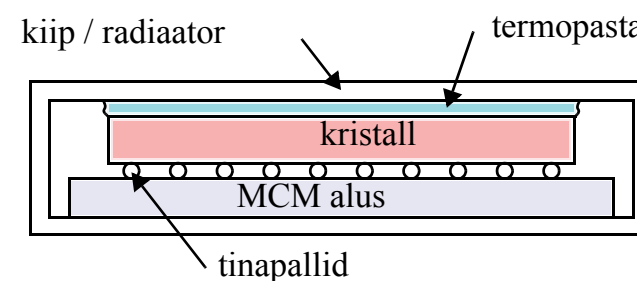
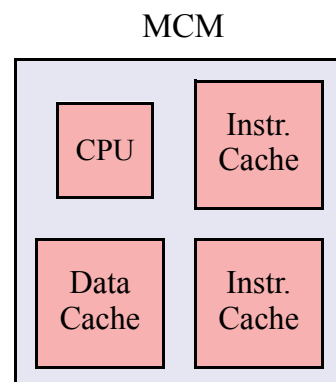


Termilised probleemid

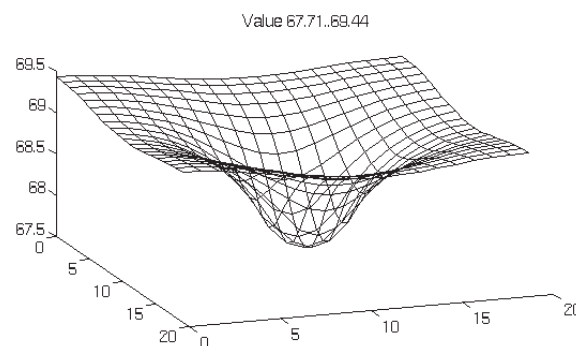
- Jahutamine

- Näidisdisain (MCM)

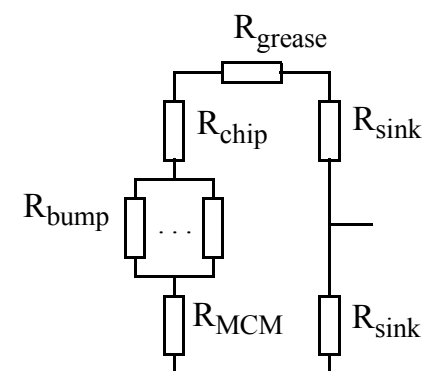
- CPU - 68 mm^2 , cache - 112 mm^2
- koguvõimsus - 72 W
- soojuse eemaldamine
 - kristall (GaAs): 46 W/mK
 - väljaviigud (tinapallid):
 $d 0.1 \text{ mm}$, samm 0.25 mm , 36 W/mK (CPU 361 & cache 441)
 - termopasta:
paksus 0.2 mm , 1.1 W/mK
 - MCM alus (alumina):
 $27 \times 27 \text{ mm}$, 20 W/mK
 - kiip/radiaator (Al): 238 W/mK



Temperatuuri jaotus väljaviigu ümbruses



Soojusvoo mudel



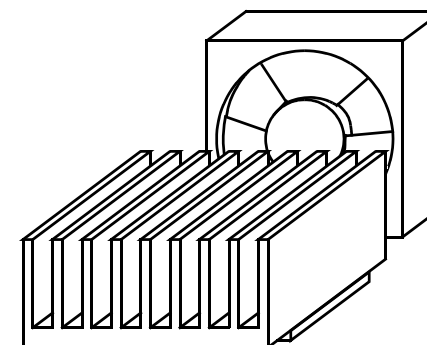
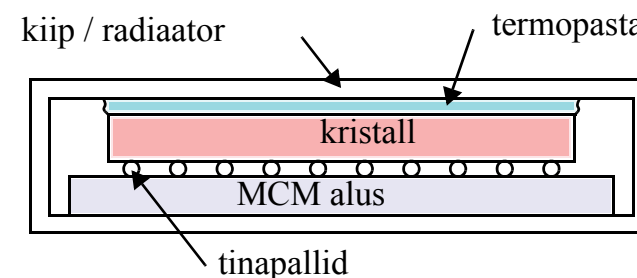
Termilised probleemid

- **Jahutamine (järg)**
 - **temperatuuride vahed**
 - väljaviik & MCM: 20-25 K
 - koos termopastaga: 15-16 K
 - **radiaator**
 - vaba õhuvool: 5 W/m²K
 - sundjahutus (ventilaator): 50 W/m²K
 - kristalli temperatuur ≤ 80°C
 - radiaatori pindala [cm²]:

Radiaatori temperatuur [°C]	Keskkonna temperatuur			
	vaba õhuvool		sundjahutus	
	50°C	30°C	50°C	30°C
64.0	10286	4237	1029	424

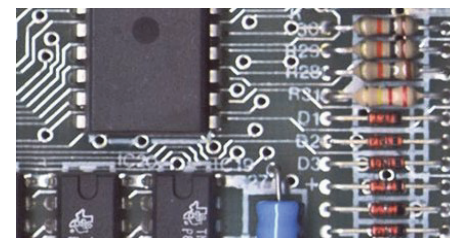
- **Termiline paisumine**

- kristall (GaAs): $6.8 \cdot 10^{-6} \text{ K}^{-1}$ (paisub kuni 1.4 μm); MCM alus (alumina): $7.7 \cdot 10^{-6} \text{ K}^{-1}$



Trükkplaadid

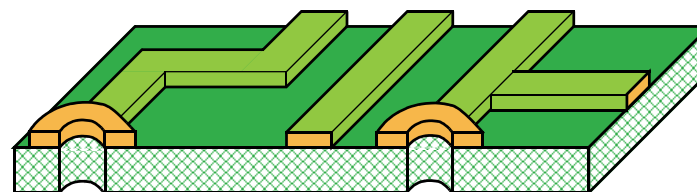
- **PCB (Printed Circuit Board)**
- **Valmistamine ja projekteerimine**
 - töökindlus, maksumus, jõudlus...
 - **Komponendid**
 - mikroskeemid, transistorid, takistid, kondensaatorid jne.
 - Ühendused
 - Liidesed
 - Kinnitused
- **Trükkplaadi valmistamine**
- **Komponentide paigaldamine (ja kinnitamine)**
- **Elektriliste ühenduste loomine (nt. jootmine)**



Trükkplaatide valmistamine

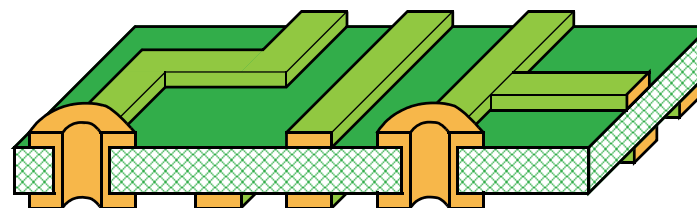
- Vasega (Cu) kaetud tekstoliit (klaasriie+epoksüvaik)

Ühekihiline



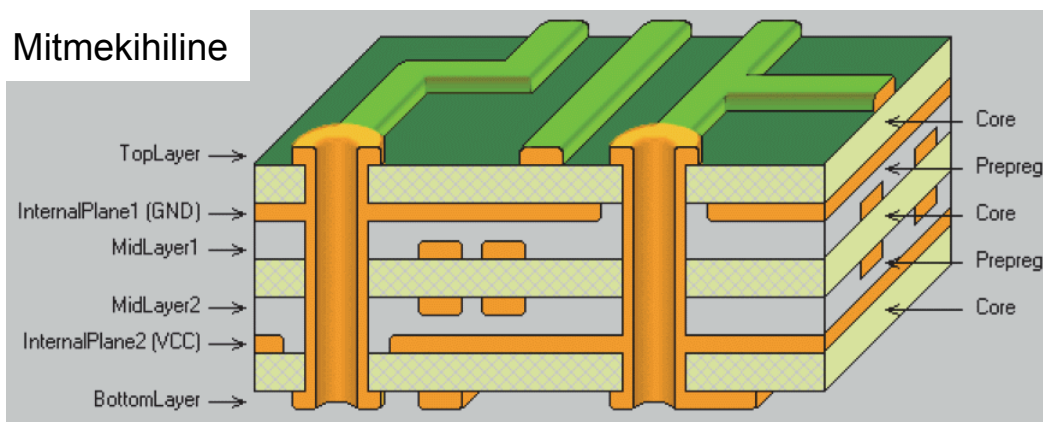
- Ühekihiline trükkplaat
- ühendusrajad (alumine pool)

Kahekihiline



- Kahekihiline trükkplaat
- ühendusrajad
- metalliseeritud läbiviigud

Mitmekihiline



- Mitmekihiline trükkplaat
- mitu kahekihilist plaati
- läbiviikude asukohad!



Trükkplaatide valmistamine

Väikeseeriad / üksikeksemplarid

- **Täielikult vasega kaetud plaat (1- või 2-kihiline)**
- **Läbiviikude puurimine (drilling)**
- **Läbiviikude galvaaniline metalliseerimine**
- **Ühendusradade loomine == liigse vase eemaldamine**
 - **liigse metalli söövitamine (etching)**
 - 1) **kaitsekihi peale kandmine (radade positiivkujutis)**
 - a) **kaitselaki / -värvi joonistamine / siiditrükk**
 - b) **printimine (fototundlik materjal, termokiled jne.)**
 - 2) **söövitamine (FeCl_3 , HNO_3 jne.)**
 - **liigse metalli välja freesimine (milling)**
- **Komponentide paigaldamine**
 - **vajaduse korral ka kinnitamine (nt. liimimine)**
- **Jootmine**
 - **mehhaniseeritud (tinalaine) või käsitsi**



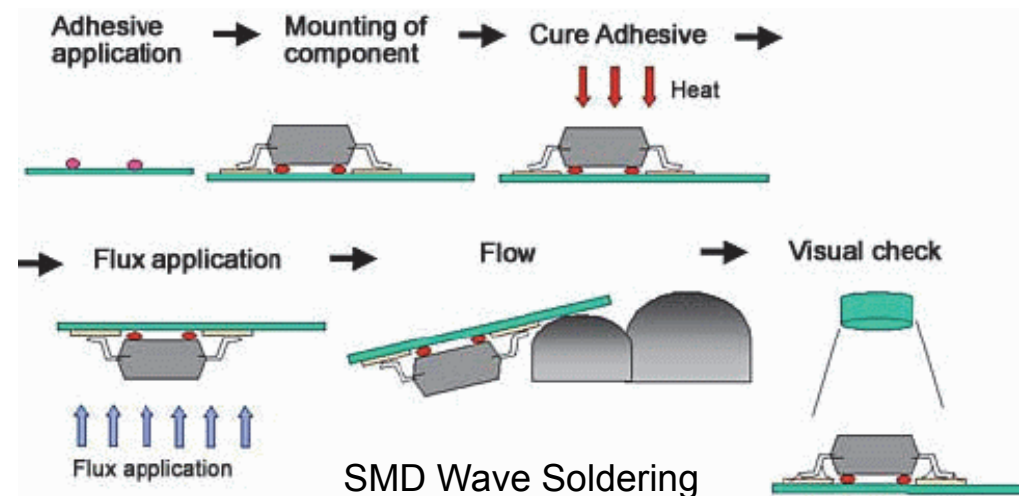
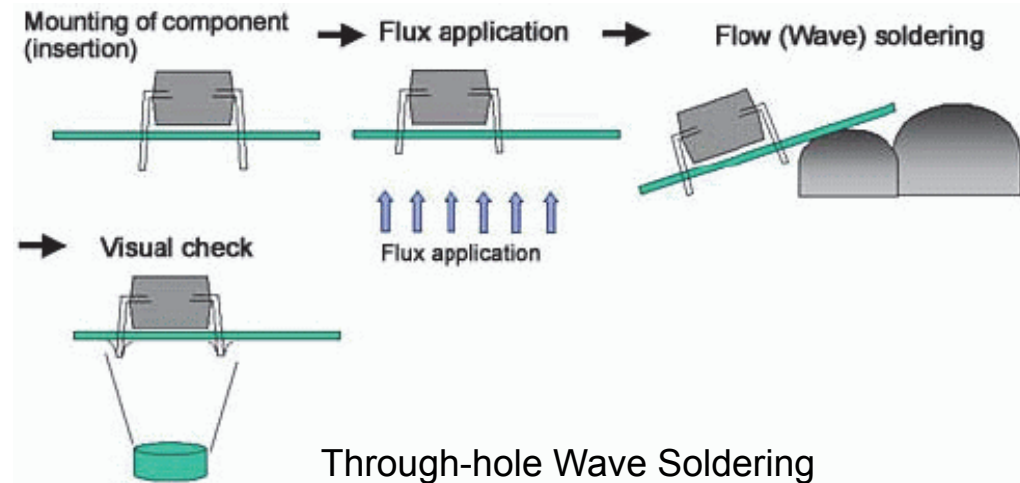
Trükkplaatide valmistamine

Suurseeriad

- **Läbiviikude puurimine (metalliga katmata plaat)**
- **Ühendusradade loomine == vasekihi galvaaniline kasvatamine**
 - keemiliselt kantakse peale õhuke vasekiht
 - radade asukohtade trükkimine (fotolitograafia)
 - galvaaniline radade kasvatamine vajaliku paksuseni (tagab ka läbiviikude metalliseerimise)
 - liigse vase eemaldamine (söövitamine)
- **Kaitsekihi (-laki) ja jootevedeliku/-tinaga katmine**
- **Komponentide (mehhaniseeritud) paigaldamine**
 - vajaduse korral ka kinnitamine (nt. liimimine)
- **Jootmine**
 - mehhaniseeritud

Trükkplaatide valmistamine

- **Valmistamine**
 - komponentide kinnitamine
 - jootmine
 - jootevedelik / -tina
 - termilised probleemid
 - suured vasespinnad
 - komponentide ülekuumenemine
- kvaliteedi kontroll
 - visuaalne
- lõppviimistlus
 - puhastamine
 - kaitselakkimine
- lõpptestimine
 - funktsionaalsuse kontroll



Trükkplaatile valmistamine

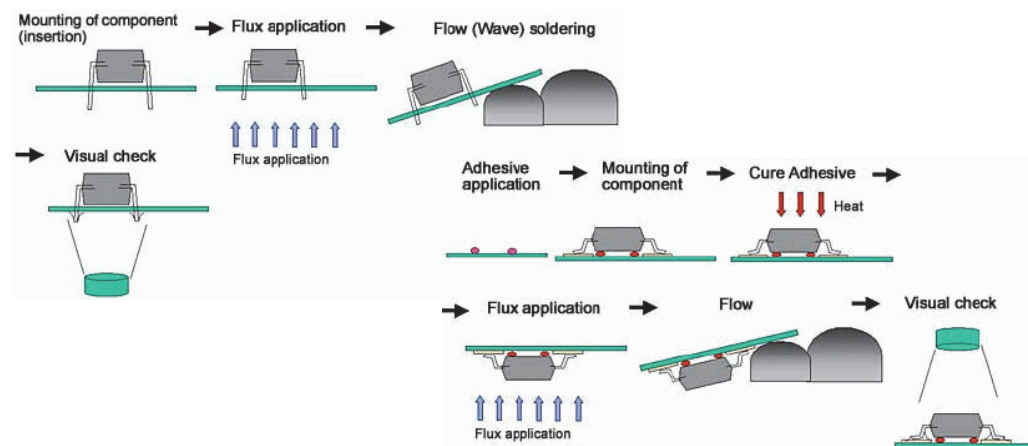
Wave Soldering

Electro Soft Inc.

<https://www.youtube.com/watch?v=inHzaJIE7-4>

Agrowtek Inc.

<https://www.youtube.com/watch?v=VWH58QrprVc>



SMD Reflow Soldering

GIGABYTE factory tour

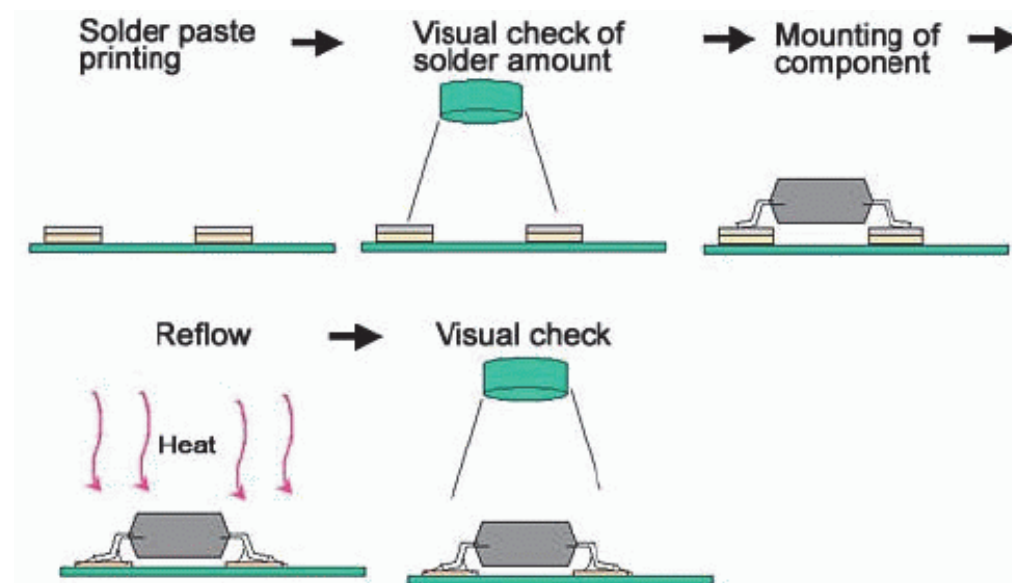
<https://www.youtube.com/watch?v=Va3Bfn4inA>

Tutorial

<https://www.youtube.com/watch?v=gu0v8lfLcKg>

SMD reflow at home

<https://www.youtube.com/watch?v=U48Nose31d4>





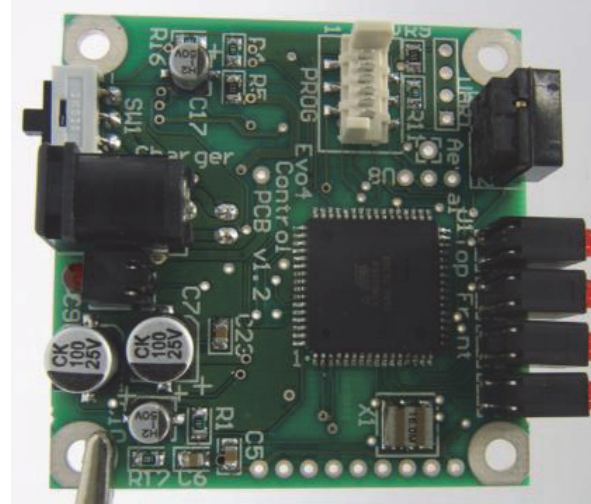
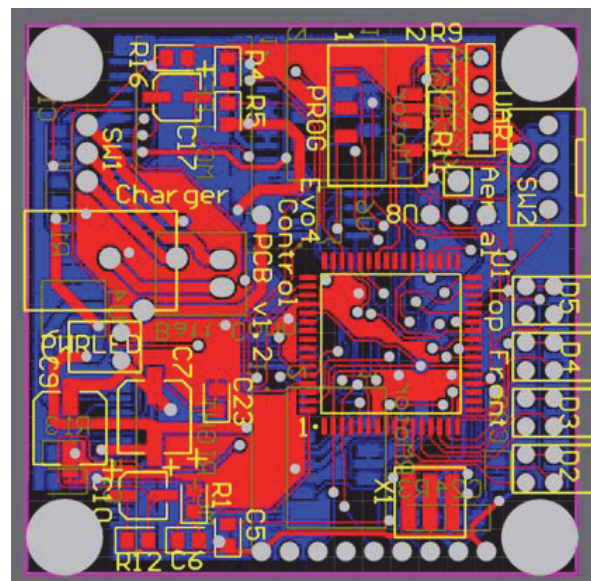
Trükkplaatide valmistamine

Praktilisi nõuandeid

- Mõõtühik on *mil* (1/1000 tolli, st. 0,0254 mm)
- Augud
 - mida väiksem auk, seda kallim plaat
 - väikseimad augud võiksid olla 0,5 mm või suuremd
 - mida paksem plaat, seda suuremad augud – 2 mm plaat -> mitte alla 0,4 mm augud
- Ühendusrajad
 - liiga kitsad rajad ja radadevahed tekitavad probleeme
 - soovitatav laius 0,25 mm (10 mil)
- Polügonid (suured pinnad, nt. maakiht)
 - kasutatakse ekraaniks, jahutamiseks jne.
 - väikseim vahe polügoni ja radade vahel vähemalt 0,25 mm
- Jootemask
 - kõikide jooteplastide jaoks peaks olema jootemaskis (kaitselakk) vastav auk
- Markeering
 - ei tohi sattuda jootekohtadele, täpsus ~0,5 mm

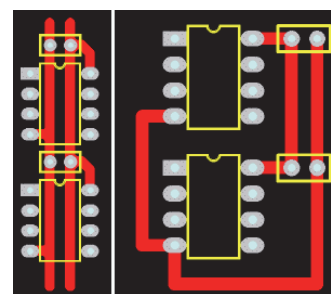
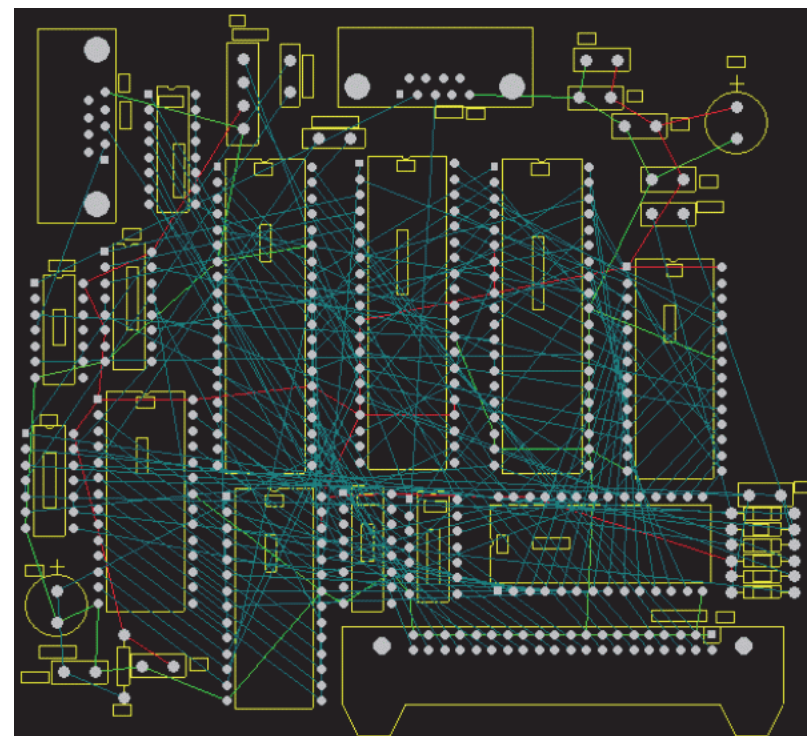
Trükkplaatide projekteerimine

- **Skeemist moodulini**
 - Skeemi sisestamine
 - Komponentide paigaldamine
 - siinide asukohad
 - tugikomponendid
 - Ruutimine
 - harakapesa (rat-nest) asendamine traatidega
 - toiteühendused
- **Kontroll (DRC)**
 - radade mõõtmised
 - radadevahelised kaugused
 - aukudevahelised kaugused
 - jne.

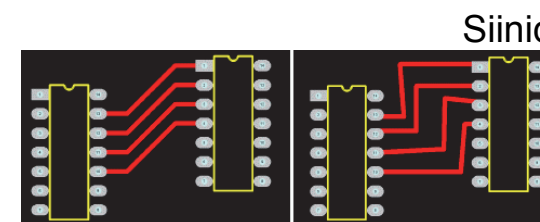


Trükkplaatide projekteerimine

- **Projekteerimine**
- **PCB Design Tutorial**
 - David L. Jones
 - <http://www.alternatezone.com/>
- **Mõningaid soovitusi**
 - **Toite ühendamine**
 - filterkondensaatorid
 - **Siinide ühendamine**
 - **Mitmekihilised plaadid**
 - läbiviikude tüübid – läbi terve plaadi, (osaliselt) peidetud
 - läbiviikude asukohad – sünkroniseerimine
- **EAGLE**
 - Easily Applicable Graphical Layout Editor
 - CadSoft Online – <http://www.cadsoft.de/>



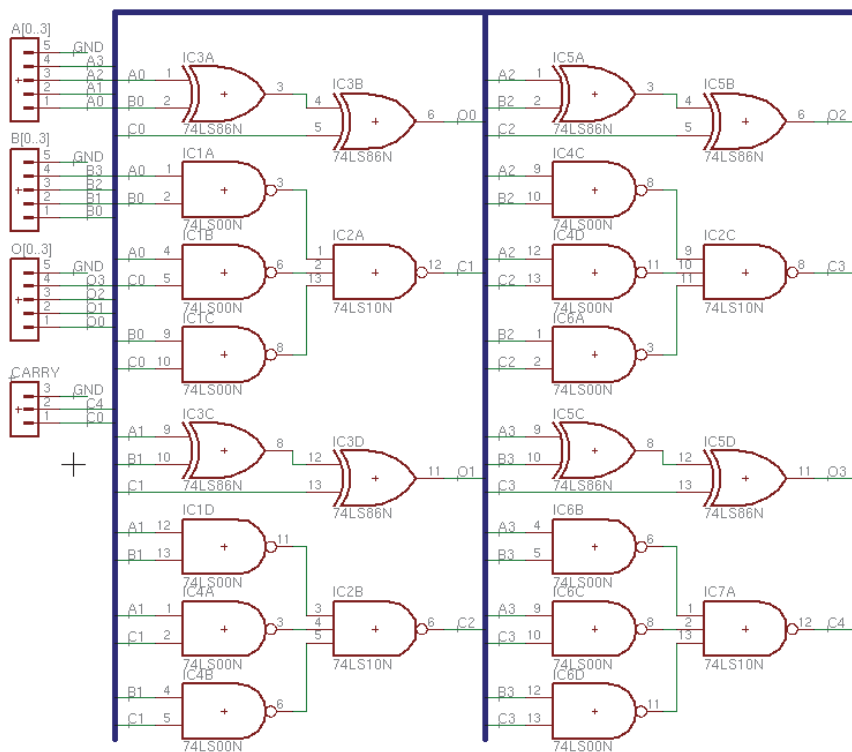
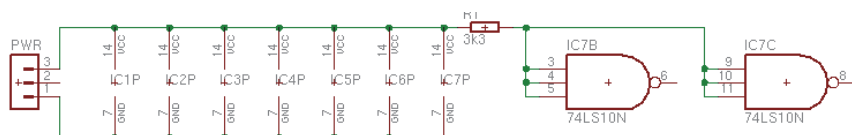
Toide



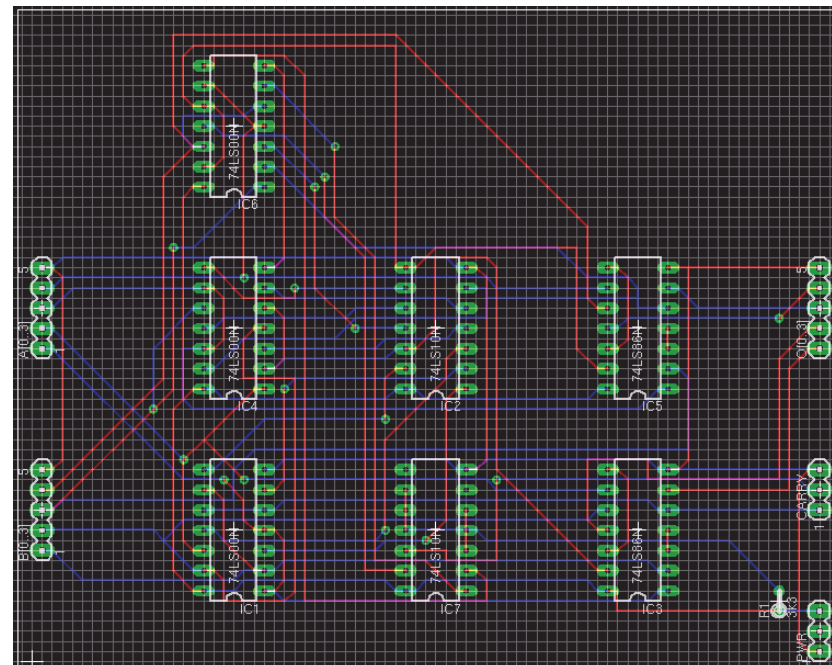
Siinid

Näidisdisain – 4-bitine summaator

7 kiipi: 2x(4x2-XOR), 3x(4x2-NAND), 2x(3x3-NAND)



36 ahelat, 82 ühendust, 17 läbiviiku



36 ahelat, 82 ühendust, 64 läbiviiku

